

Introduction to Process Simulation: Using TSUPREM4

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EE143-Process Simulation

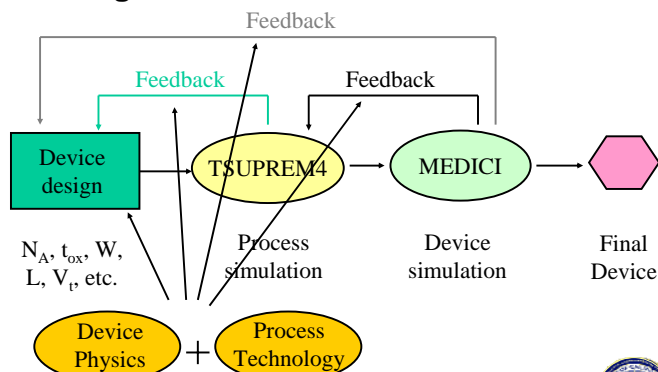


Why Simulation?

- Process (TSuprem4) and device (Medici) simulators are indispensable tools in the device community
- Simulators provide insight on processing steps, device physics, feedback in device design, and are important areas of research
- *Simulation does not replace design!!!*



Design Flow



TSUPREM-4

- Simulates all major process steps in 2-D
 - Deposition
 - Implant
 - Oxidation
 - Diffusion
 - Lithography
 - Etc.

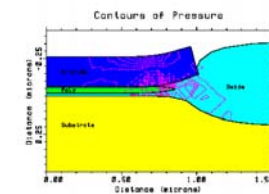


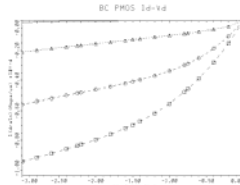
Figure 5.30 Contours of hydrostatic pressure in final poly-buffered LOCOS structure

- Analytical and empirical models are used to predict device cross-sections and doping profiles



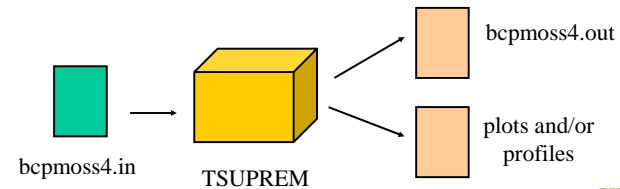
MEDICI

- Simulates electrical characteristics of a given 2-D device structure
- Takes voltage bias at each electrode
- Program solves Poisson's equation to determine the potential distribution in a device
- Applies various models for carrier transport to determine the current at each terminal



Getting started

- TSUPREM4 and MEDICI both take a text file as input
- Outputs text that is piped to the terminal
- Output includes simulation information and user-specified data (plots, cross-sections, values, etc.)



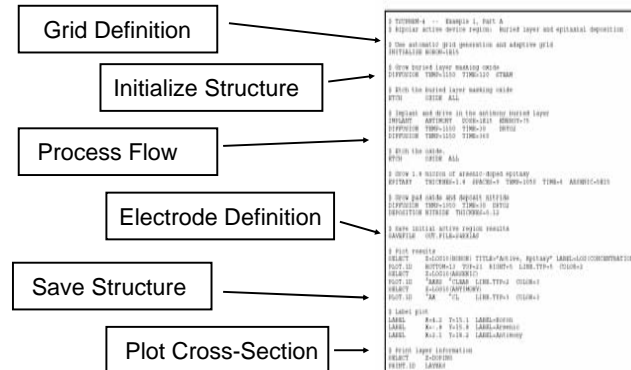
Getting started

- Use text editor to create decks (vi, emacs, pico)
- Simulators are run off UNIX workstation or PC with Hummingbird
- <https://inst.eecs.berkeley.edu/cgi-bin/pub/cgi?file=tcad.help>
 - /share/b/bin/tsuprem4
 - Set path = (\$path /share/b/bin)
- Pop up windows:
 - setenv DISPLAY [ip_address_or_computer_name]

% tsuprem4 [input_file_name]

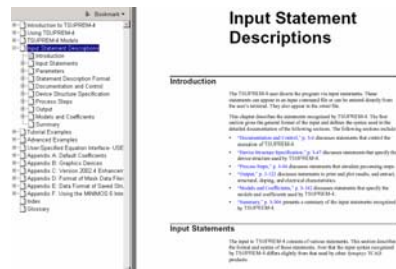


Anatomy of a TSUPREM Deck



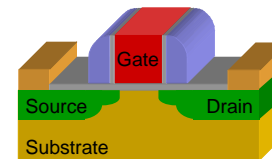
Simulator Manuals

- TSUPREM and Medici Manuals are valuable resource for Input Statements and Examples
- Can find Input Statement Fields and Capabilities



Example: Basic CMOS Process

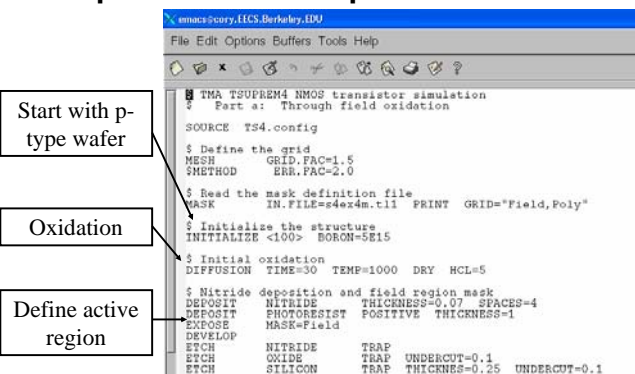
- Let's design a NMOSFET ($L=0.65 \mu\text{m}$)



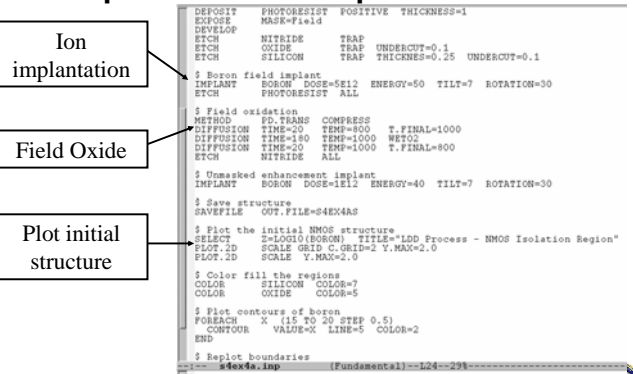
(From example deck s4ex4*.inp)
 /share/instsw/synopsys/cad/tcad-suprem-4_v2002.4/
 tsuprem4_2002.4.0/examples/



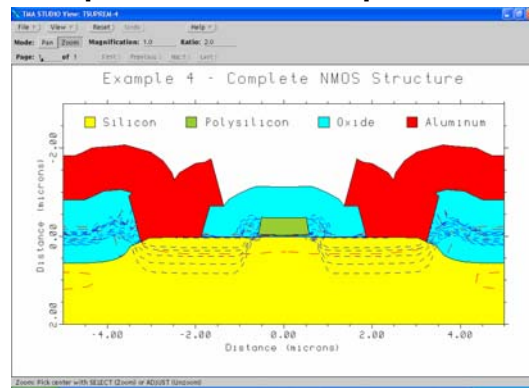
Example: TSUPREM Input



Example: TSUPREM Input

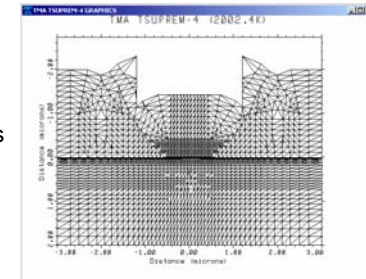


Example: TSUPREM Output



Grid Structure

- Divides the device cross-section into a 2-D array of discrete grid points
- Necessary for SUPREM to calculate solutions
- A finer grid is more accurate but also increases simulation time



Defining the Grid

- grid.fac is the most straightforward way to vary grid density
 - ```
$ Set grid spacing and accuracy parameters
MESH GRID.FAC=1.5
SMETHOD ERR.FAC=2.0
```
- Grid spacing can be varied spatially:
  - Line
  - Eliminate
  - Boundary
  - Region
- Grids can also be defined with saved structure files



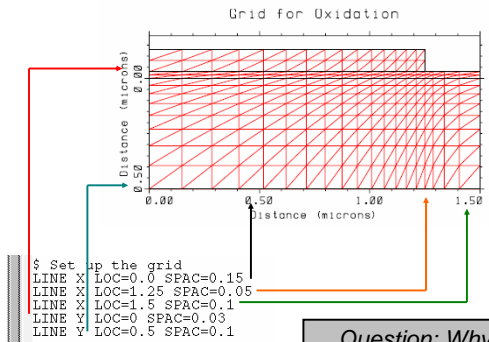
## Grid example: Local Oxidation

```
emacsvdevice1.IICS.Berkeley.CDU
File Edit Options Buffers Tools Help

$ TSUPREM-4 narrow window example
$ Part 1: Oxide shape
$ Set up the grid
LINE X LOC=0.0 SPAC=0.15
LINE X LOC=1.25 SPAC=0.05
LINE X LOC=1.5 SPAC=0.1
LINE Y LOC=0 SPAC=0.03
LINE Y LOC=0.5 SPAC=0.1
$ No impurities, for faster oxidation simulation
INITIALIZE
$ Deposit pad oxide and define nitride mask
DEPOSITION OXIDE THICKNESS=0.03 SPACES=2
DEPOSITION NITRIDE THICKNESS=0.10 SPACES=2
ETCH NITRIDE RIGHT PLX=1.25
```



## Grid example: Local Oxidation



Question: Why do we want the grid to be denser on the right side?



## Other tips

- Constants make it easy to change device parameters
- Useful to plot various cross sections
- When material is deposited, grid spaces should be specified
- Have fun!!!



## Questions?

